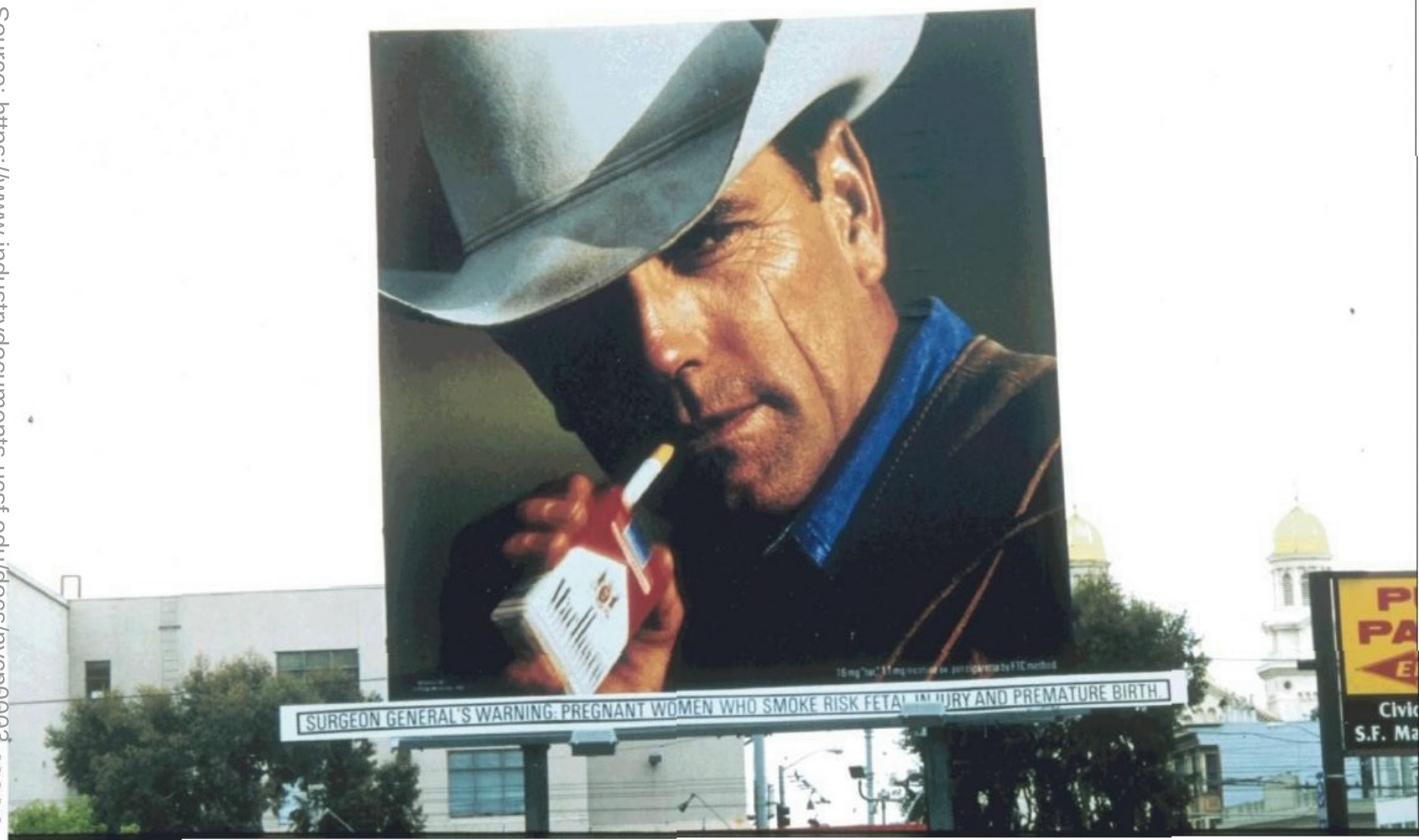

Source: https://www.industrydocuments.ucsf.edu/docs/nyc20003 40064